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INFORMATION DISCLOSURE STATEMENT BY APPLICANT			Applicant(s)				
(Use several sheets if necessary)			Martin, Kirk				
			Filing Date	Group			
			July 10, 2001				
U.S. Patent Documents							
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA						
Foreign Patent Documents							
		Document	Date	Country	Class	Subclass	Technology Yes <input checked="" type="checkbox"/> Translation <input type="checkbox"/>
	AB						TECHNOLOGY CENTER 2001 ED
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)							
LV	AC	Weavers, Barry A., "Chemical Thinning of Silicon for Emission Microscopy Using Multi Etch--An Introduction," Nisene Technology Group, Inc., B&G International Division, August 2000, pp. 1-6.					
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	AE	Hypervision, "Sensor and Optics Technology: BEAMS and Mercad Telluride (MCT)," Hypervision Inc., 2000, pp. 1-8.					
	AF	Hypervision, "Chip UnZip Backside Preparation Tool," Hypervision Inc., 2000, pp. 1-4.					
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	AH	Adams, Tom, "Backside Emission Microscopy of Wafers," News and Analysis @Semiconductor Online, February 28, 2000, pp. 1-3.					
	AI	Adams, Tom, "Bringing the Emission Microscope to the Test Floor," News and Analysis @Semiconductor Online, July 1, 1999, pp. 1-4.					
	AJ	Hypervision, "BEAMS™ (Backside Emission Analysis Microscope System)", Hypervision Inc., 1998, p.1.					
	AK	Clark, Scott, MSCE, "Etching Silicon Dioxide with Aqueous HF Solutions," Silicon Dioxide Etch, Bold Technologies, January 29, 2001, pp. 1-5.					
	AL	Bold Technologies, "Manual Equipment", Bold Technologies, Inc., 1998-2000, pp. 1-3.					
LV	AM	Nisene Technology Group, "MultiEtch System," Nisene Technology Group, Inc., July 12, 2000, pp. 1-4.					
Examiner LAN VINH		Date Considered		2/3/2003			
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.							